



On the nonlinear primary resonances of a piezoelectric laminated micro system under electrostatic control voltage



Hamed Raeisifard ^{a,*}, Mehdi Zamanian ^b, Mansour Nikkhah Bahrami ^c,
Aghil Yousefi-Koma ^d, Hafez Raeisi Fard ^e

^a Department of Industrial and Mechanical Engineering, Qazvin Branch, Islamic Azad University, Qazvin, Iran

^b Faculty of Engineering, Kharazmi University, Mofatteh Avenue, PO Box 15719-14911, Tehran, Iran

^c Department of Mechanical and Aerospace Engineering, Tehran Science and Research Branch, Islamic Azad University, Tehran, Iran

^d School of Mechanical Engineering, College of Engineering, University of Tehran, Tehran, Iran

^e Mechanical, Aerospace and Nuclear Engineering Department, Rensselaer Polytechnic Institute, Troy, NY, USA

ARTICLE INFO

Article history:

Received 4 September 2013

Received in revised form

25 April 2014

Accepted 27 May 2014

Handling Editor: I. Lopez Arteaga

Available online 30 June 2014

ABSTRACT

In this article, a comprehensive nonlinear analysis for a piezoelectric laminated micro system around its static deflection is presented. This static deflection is created by an electrostatic DC control voltage through an electrode plate. The micro system beam is assumed as an elastic Euler-Bernoulli beam with clamped-free end conditions. The dynamic equations of this model have been derived by using the Hamilton method and considering the nonlinear inertia, curvature, piezoelectric and electrostatic terms. The static and dynamic solutions have been achieved by using the Galerkin method and the multiple-scales perturbation approach, respectively. The results are compared with numerical and other existing experimental results. By studying the primary resonance excitation, the effects of different parameters such as geometry, material and excitations voltage on the system's softening and hardening behaviors are evaluated. In a piezo-electrically actuated micro system it was showed that because of existence of curvature and inertia nonlinear terms a small change in excitation amplitude can lead to the formation and expansion of nonlinear response. In this paper, it is demonstrated that by applying an electrostatic DC control voltage, these nonlinearities can be controlled and altered to a linear domain. This model can be used to design a nano or micro-scale smart device.

© 2014 Elsevier Ltd. All rights reserved.

1. Introduction

The micro-systems, which can be fabricated due to recent advances in integrated circuits, include moving parts such as beams, plates, membranes or other mechanical components. Because of their small size, the easy creation of relatively large amplitude oscillations and the existence of strong effects by nonlinear sources, these components exhibit nonlinear behaviors. The emergence of phenomena such as softening and hardening, hysteresis, jumps in resonance frequency, the existence of more than one stable state, sensitivity to initial conditions and dynamic pull-in in these devices are all cases that cannot be handled by linear theories. Therefore, nonlinear models and theories should be employed to obtain precise

* Correspondence to: No. 6, Hekmat sharghi St, Neyestan 2 St., Pasdaran Ave., Tehran, Zip Code:1947874513, Iran. Tel.: +98 9126076763.
E-mail addresses: h.raeisifard@gmail.com (H. Raeisifard), zamanian@khu.ac.ir (M. Zamanian).

Nomenclature		
a	amplitude of system response under static condition	t_b, t_p Micro-beam and piezoelectric layer thickness, respectively
a_0	amplitude of system response under static condition at equilibrium state	T the time scale which is used to change the time into dimensionless form
$a[i] \ i=1 \dots M$	the coefficients obtained for the comparison functions in calculating v_s	T_k kinetic energy
A, \bar{A}	mixed function, conjugate of A	u micro-beam longitudinal displacement
A_b, A_p	cross section area of the micro-beam and the piezoelectric layer, respectively	v micro-beam bending displacement
$b[j] \ j=1 \dots M$	the coefficients obtained for the comparison functions in calculating φ	v_d the added dynamic deflection to v_s
$C_\eta(s)$	the magnitude of the bending moment due to the piezoelectric effects	v_s dimensionless static deflection
$C_\eta(s)$	bending stiffness of the system	$v_s[i]$ i th comparison function used for obtaining v_s
d	distance between the micro-beam and the electrode plate	V potential energy
e	stretching strain of the neutral axis bending	V_{dc} applied voltage between the micro-beam and the electrode plate
E_b, E_p	micro-beam and piezoelectric modulus of elasticity, respectively	w_b width of micro-beam and piezoelectric layer
$H(x)$	a dimensionless measure for the bending stiffness of the system	x the dimensionless form of s
H_{lp}	heaviside function at the point l_p	\bar{z} distance from the neutral axis of cross section
I_b, I_p	the second moment of area for the micro-beam and the piezoelectric layer cross section about the neutral axis, respectively, where $0 < s < l_p$,	z_n distance between the neutral axis and the midline of the micro-beam
K	summation of nonlinear terms	$\alpha_2 P_{ac} \cos(\Omega t)$ dimensionless measures for piezoelectric actuation
l	micro-beam length	$\alpha_3 V_e^2$ dimensionless measures for electrostatic actuation
l_p	distance to the left end of the piezoelectric layer from the left end of the micro-beam	γ phase of system response under static condition at equilibrium state
$m(x)$	a dimensionless measure for the mass per unit length of the micro-beam	γ_0 phase of system response under static condition
$N_e(x)$	effective nonlinear coefficient	ε strain in the cross section of the system
p^*, q^*	real and imaginary part of A	ε_0 dielectric constant between micro-system and fixed electrode
q	dimensionless bookkeeping parameter	θ rotation angle between fixed and local coordinates
Q	electrostatic load per unit length of the micro-beam	κ curvature bending of the micro-beam in the sz -plane
$syz, \bar{s} \bar{x} \bar{z}$	fixed and local coordinate systems, respectively	ρ_b, ρ_p Micro-beam and piezoelectric layer specific density, respectively
t	time	σ detuning parameter
		σ_b, σ_p micro-beam and piezoelectric layer axial stress, respectively
		τ the dimensionless form of t
		$\varphi_a[j]$ j th comparison function used for obtaining φ
		$\varphi(x)$ mode shape of the system
		ω natural frequency of system

and correct results in these cases. In common micro-systems that include micro-switches and micro-resonators, the main mechanical component is a micro-beam. By the excitation of a DC voltage, a fixed static deformation is formed in this micro-beam and then by using an AC harmonic voltage, the micro-beam's vibration modes are excited, and the micro-beam starts to oscillate at its natural frequency. These voltage excitations can be applied electrostatically or piezoelectrically. In electrostatic excitation with a sufficiently high voltage, pull-in phenomenon can occur, in which case, the micro-beam becomes unstable and sticks to the electrode plate in front of it [1]. The effect of nonlinear terms in governing equations of an electrostatically excited micro-cantilever is presented in many studies. Researchers in their work demonstrated that the effect of nonlinear terms due to inertia and geometry appears as hardening and the effect of electrostatic forces appear as softening on vibration behavior of a micro-system [2,3]. Due to their low weight, fast response, low energy consumption and high bandwidth performance, piezoelectric materials have been extensively used in microsystems as actuators and sensors [4]. Li et al. and Dick et al. in separate studies showed that a piezoelectrically actuated micro system demonstrated a hardening behavior. They use multiple scale perturbation method to solve the dynamic equations [5,6]. By using the Lumped parametric model, Lee et al. studied the mechanical behavior of a micro-cantilever subjected to piezoelectric excitation. They obtained their numerical results by solving the nonlinear Duffing's equation with one degree of freedom and compared them with experimental findings. They concluded that the resonance frequency displays hysteretic behavior as the DC voltage changes,

Download English Version:

<https://daneshyari.com/en/article/287527>

Download Persian Version:

<https://daneshyari.com/article/287527>

[Daneshyari.com](https://daneshyari.com)